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Substitute for form 1449A/PTO

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>					
Sheet	1	of	5	Attorney Docket Number	P121-63-03

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Document ²	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ³
		Office ³	Number ⁴				
	B1	2002/0177319	A1	Chou	11/28/2002		
	B2	6,518,189	B1	Chou	2/11/2003		
	B3	6,828,244	B2	Chou	12/7/2004		
	B4	6,809,356	B2	Chou	10/26/2004		
	B5	2004/0197843	A1	Chou et al.	10/7/2004		
	B6	2004/0156108	A1	Chou et al.	8/12/2004		
	B7	2004/0137734	A1	Chou et al.	7/15/2004		
	B8	2004/0131718	A1	Chou et al.	7/8/2004		
	B9	2004/0118809	A1	Chou et al.	6/24/2004		
	B10	2004/0046288	A1	Chou	3/11/2004		
	B11	2003/0080472	A1	Chou	5/1/2003		
	B12	2003/0034329	A1	Chou	2/20/2003		
	B13	2002/0042027	A1	Chou et al.	4/11/2002		
	B14	2004/0116548	A1	Willson et al.	6/17/2004		
	B15	5,594,042		Glover et al.	1/14/1997		
	B16	5,629,095		Bujanowski et al.	5/13/1997		
	B17	5,861,467		Bujanowski et al.	1/19/1999		
	B18	5,331,020		Brown et al.	7/19/1994		

Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>6/2/05</i>
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<p>Substitute for form 1449A/PTO</p> <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p><i>(use as many sheets as necessary)</i></p>				<p><i>Complete if Known</i></p>	
				APPLICATION NUMBER	10/789,319
				FILING DATE	02/27/2004
				FIRST NAMED INVENTOR	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	2	of	5	Attorney Docket Number	P121-63-03

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Examiner Signature	<i>Mark Hammey</i>	Date Considered	6/1/05
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			
	B38	Chou et al., Nanoimprint Lithography, Journal of Vacuum Science Technolgy B 14(16), pp. 4129-4133, 11/1/1996			

<i>MJ</i>	B38	Chou et al., Nanoimprint Lithography, Journal of Vacuum Science Technolgy B 14(16), pp. 4129-4133, 11/1/1996	
	B39	Colburn et al., Development and Advantages of Step-and-Flash Lithography, Solid State Technology, 7/1/2001	
	B40	Colburn et al., Characterization and Modeling of Volumetric and Mechanical Properties for Step and Flash Imprint Lithography Photopolymers, Journal of Vacuum Science Technology. Vol b. 19(6), 11/1/2001	
	B41	Yu et al., Properties of Fluorinated Amorphous Diamond Like Carbon Films by PECVD, Applied Surface Science 219 (3-4); pp. 228-237, 12/1/2003	
	B42	Compon et al., Electroanalysis at Diamond-Like and Doped-Diamond Electrodes, Electroanalysis 15(17); pp. 1349-1363, 9/1/2003	
	B43	Mansano et al., Protective Carbon Layer for Chemical Corrosion of Stainless Steel, Diamond and Related Materials 12 (3-7); pp. 749-752, 3/1/2003	
	B44	Butter et al., Production and Wetting Properties of Fluorinated Diamond-Like Carbon Coatings, Thin Solid Films, 311(1-2); pp. 107-113, 12/31/1997	
	B45	Hakovirta et al., Heat Resistance of Fluorinated Diamond-Like Carbon Films, Diamond and Related Materials 10(8); pp. 1486-1490, 8/1/2001	
<i>MJ</i>	B46	Zhu et al., The Improvement of the Oxidation Resistance of TiAl Alloys by Fluorine Plasma-Based Ion Implantation, Surface and Coatings Technology 158; pp. 502-507, 9/1/2002	

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				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03

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Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			
T ²					

<i>MJ</i>	B47	Yao et al., Structural, Mechanical and Hydrophobic Properties of Fluorine-Doped Diamond-Like Carbon Films Synthesized by Plasma Immersion Ion Implantation and Deposition (PIII-D), Applied Surface Science 230; pp. 172-178, 4/17/2004	
<i>J</i>	B48	Bailey et al., Step and Flash Imprint Lithography: Defect Analysis, Journal of Vacuum Science, B 19(6), pp. 2806-2810, 11/1/2001	
<i>J</i>	B49	Bailey et al., Step and Flash Imprint Lithography: Template Surface Treatment and Defect Analysis, Journal of Vacuum Science, B 18(6), pp. 3572-3577, 11/1/2000	
<i>MJ</i>	B50	Schneider et al., Stripes of Partially Fluorinated Alkyl Chains: Dipolar Langmuir Monolayers	

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Sheet 1 of 2

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U.S. PATENT DOCUMENTS

Examiner Signature	<i>Mark Lammes</i>	Date Considered	<i>6/16/05</i>
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<i>MJ</i>	C5	Data Sheet for MAK (Methyl n-Amyl Ketone), www.sp-chem.com/fine_e , 1/1/2003	
	C6	Data Sheet for gamma-Glycidoxypropyltrimethoxysilane, www.powerchemical.net/3100.htm , 12/5/2003	
	C7	Silicon or Silica, www.mii.org/Minerals/photosil , 3/31/2005	
	C8	Electronic Devices and Circuits, people.deas.harvard.edu/~jones/es154/lectures/lecture_2/materials/materials.html , 3/31/2005	
	C9	Data Sheet for Cymel 303ULF, www.cytec.com , 12:00:00 AM	
	C10	Data Sheet for Cycat 4040, www.cytec.com , 12:00:00 AM	
	C11	International Chemical Safety Card for p-Tolueneulfonic Acid, www.itcilo.it/english/actrav/telearn/osh/ic/104154.htm , 12/5/2003	
	C12	Data Sheet for p-Toluenesulfonic Acid, NIOSH Manual of Analytical Methods (NMAM), Fourth Edition, 12:00:00 AM	
	C13	Data Sheet for Dow Corning Z-6018, , 12:00:00 AM	
<i>MJ</i>	C14	Data Sheet for Methyl Amyl Ketone, www.arb.ca.gov/db/solvents/solvent_pages/Ketones-HTML/methyl_amyl.htm , 3/31/2005	

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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-CONTAINING MATERIAL						
<p>Application Number: 10/789319 *10/789319*</p> <p>Confirmation Number: 9202</p> <p>First Named Applicant: Frank Xu</p> <p>Attorney Docket Number: P121-63-03</p> <p>Art Unit: 1712</p> <p>Examiner: Marc S. Zimmer</p> <p>Search string: (5737064).pn.</p>							
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
<i>M</i>	1	5737064	1998-04-07	Inoue et al.			
Signature							
Examiner Name				Date			
<i>Marc Zimmer</i>				6/2/05			



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		Number	Kind Code ² (if known)			
	A1	3,527,062		Bellnski et al.	09-08-1970	
	A2	3,783,520		King	01-08-1974	
	A3	3,807,027		Heisler	04-30-1974	
	A4	3,807,029		Troeger	04-30-1974	
	A5	3,811,665		Seelig	05-21-1974	
	A6	4,062,600		Wyse	12-13-1977	
	A7	4,070,116		Frosch et al.	01-24-1978	
	A8	4,098,001		Watson	07-04-1978	
	A9	4,119,688		Hiraoka	10-10-1978	
	A10	4,155,169		Drake et al.	05-22-1979	
	A11	4,201,800		Alcorn et al..	05-06-1980	
	A12	4,202,107		Watson	05-13-1980	
	A13	4,267,212		Sakawaki	05-12-1981	
	A14	4,326,805		Feldman et al.	04-27-1982	
	A15	4,337,579		De Fazio	07-06-1982	
	A16	4,355,469		Nevins et al.	10-26-1982	
	A17	4,414,750		De Fazio	11-15-1983	
	A18	4,426,247		Toshiakai et al.	01-17-1984	
	A19	4,440,804		Milgram	04-03-1984	
	A20	4,451,507		Beltz et al.	05-29-1984	
	A21	4,507,331		Hiraoka	03-26-1985	
	A22	4,544,572		Sandvig et al.	10-01-1985	
	A23	4,552,832		Blume et al.	11-12-1985	
	A24	4,552,833		Ito et al.	11-12-1985	
	A25	4,600,309		Fay	07-15-1986	
	A26	4,610,442		Oku et al.	09-09-1986	
	A27	4,657,845		Frechet et al.	04-14-1987	
	A28	4,692,205		Sachdev et al.	09-08-1987	
	A29	4,694,703		Routson	09-22-1987	
	A30	4,707,218		Giammarco et al.	11-17-1987	
	A31	4,724,222		Feldman	02-09-1988	
	A32	4,731,155		Napoli et al.	03-15-1988	
	A33	4,737,425		Lin et al.	04-12-1988	
	A34	4,763,886		Takei	08-16-1988	
Examiner Signature	<i>Marc S. Zimmer</i>			Date Considered	<i>6/2/05</i>	

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	A35	4,772,878		Kane	09-20-1988	
	A36	4,808,511		Holmes.	02-28-1989	
	A37	4,826,943		Ito et al.	05-02-1989	
	A38	4,846,931		Gmitter et al.	07-11-1989	
	A39	4,848,179		Ubhayakar	07-18-1989	
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	A41	4,857,477		Kanamori	08-15-1989	
	A42	4,883,561		Gmitter et al.	11-28-1989	
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	A44	4,891,303		Garza et al.	01-02-1990	
	A45	4,908,298		Hefferon et al.	03-13-1990	
	A46	4,909,151		Fukui et al.	03-20-1990	
	A47	4,919,748		Bredbenner et al.	04-24-1990	
	A48	4,921,778		Thackeray et al.	05-01-1990	
	A49	4,929,083		Brunner	05-29-1990	
	A50	4,931,351		McColgin et al.	06-05-1990	
	A51	4,959,252		Bonnebat et al.	09-25-1990	
	A52	4,964,145		Maldonado	10-16-1990	
	A53	4,964,945		Calhoun et al.	10-23-1990	
	A54	4,976,818		Hashimoto et al.	12-11-1990	
	A55	4,980,316		Huebner	12-25-1990	
	A56	4,999,280		Hiraoka	03-12-1991	
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	A59	5,071,694		Uekita et al.	12-10-1991	
	A60	5,072,126		Progler	12-10-1991	
	A61	5,073,230		Maracas et al.	12-17-1991	
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	A63	5,108,875		Thackeray et al.	04-28-1992	
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Examiner Signature

Marc Zimmer

Date Considered

6/16/05

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document: MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
	A69	5,155,749		DiMilia et al.	10-13-1992	
	A70	5,169,494		Hashimoto et al.	12-08-1992	
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	A102	5,417,802		Obeng	05-23-1995	

Examiner Signature

Marc J. Jernigan

Date Considered

6/26/05

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Sheet

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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.

Attorney Docket Number P121-63-03

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Examiner
Signature*Marc Zimmer*Date
Considered*6/2/05*

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Sheet

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Complete if Known	
Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

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		Number	Kind Code ² (if known)			
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	A138	5,753,014		Van Rijn	05-19-1998	
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	A161	5,948,219		Rohner	09-07-1999	
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Examiner Signature	Marc Summers			Date Considered	6/1/05	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT					
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Sheet	6	of	25		
				Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS						Complete if Known	
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY		
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<i>MJ</i>	A171	6,046,056		Parce et al.	04-04-2000	Complete if Known	
	A172	6,051,345		Huang	04-18-2000 <th data-kind="ghost"></th>		
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	A185	6,150,680		Eastman et al.	11-21-2000 <th data-kind="ghost"></th>		
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	A189	6,188,150	B1	Spence	02-13-2001 <th data-kind="ghost"></th>		
	A190	6,204,922	B1	Chalmers	03-20-2001 <th data-kind="ghost"></th>		
	A191	6,218,316	B1	Marsh	04-17-2001	Complete if Known	
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	A195	6,274,294	B1	Hines	08-14-2001 <th data-kind="ghost"></th>		
	A196	6,309,580	B1	Chou	10-30-2001	Complete if Known	
	A197	6,316,290	B1	Wensel	11-13-2001 <th data-kind="ghost"></th>		
	A198	6,326,627	B1	Putvinski et al.	12-04-2001 <th data-kind="ghost"></th>		
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	A200	6,334,960	B1	Willson et al.	01-01-2002 <th data-kind="ghost"></th>		
	A201	6,337,262	B1	Pradeep et al.	01-08-2002	Complete if Known	
	A202	6,355,198	B1	Kim et al.	03-12-2002 <th data-kind="ghost"></th>		
	A203	6,361,831	B1	Sato et al.	03-26-2002 <th data-kind="ghost"></th>		
	A204	6,383,928	B1	Eissa	05-07-2002 <th data-kind="ghost"></th>		
Examiner Signature	<i>Marc Zimmer</i>			Date Considered	<i>6/21/05</i>		

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Application Number	10/789,319
Sheet	7	of	25	Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03

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<i>MJ</i>	A205	6,387,783	B1	Furukawa et al.	05-14-2002
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	A212	6,411,010	B1	Suzuki et al.	06-25-2002
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Examiner Signature	<i>Mark J. Summers</i>			Date Considered	<i>6/1/03</i>

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INFORMATION DISCLOSURE
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Sheet

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of

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Complete if Known

Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS

Examiner Initials ¹	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.

Attorney Docket Number P121-63-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
MJ	A273	2003/0205657	A1	Voisin	11-06-2003	
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Substitute for form 1449A/PTO				Complete if Known	
				Application Number	10/789,319
				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	10	of	25	Attorney Docket Number	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					
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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

FOREIGN PATENT DOCUMENTS

Examiner Initials ¹	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office ³	Number ⁴	Kind Code ⁵ (if known)				
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	A355	WO	2004/006120		Watts et al.	01-15-2004		
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Examiner
Signature*Marc Zimmer*Date
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6/6/05

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Substitute for form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/789,319
(use as many sheets as necessary)				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	12	of	25	Attorney Docket Number	P121-63-03

FOREIGN PATENT DOCUMENTS

Examiner Signature	<i>Mark J. Sumner</i>	Date Considered	6/6/25
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Sheet

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25

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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<i>MJ</i>	A367	Abstract of Japanese Patent 02-24848, January 26, 1990	
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	A369	Abstract of Japanese Patent 55-88332, April 14, 2004	
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Examiner Signature	<i>Marc Zimmer</i>	Date Considered	6/12/05
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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<i>MJ</i>	A378	BENDER et al., "Multiple Imprinting in UV-based Nanoimprint Lithography: Related Material Issues.", Microelectronic Engineering 61 - 62 , January 1, 2002, pp. 407-413.	
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Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>1/1/05</i>
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Substitute for form 1449B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/789,319
(use as many sheets as necessary)				Filing Date	02/27/2004
Sheet	15	of	25	First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS				
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<i>MJ</i>	A389	CIBA SPECIALTY CHEMICALS, "What is UV Curing?", www.cibasc.com/image.asp?id=4040		
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Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>6/1/05</i>
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Complete If Known

Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

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Signature*Marc Zimmer*Date
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Examiner Signature

Marc Zimmer

Date Considered

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MJ	A477	TAJBAKHSH et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet.", American Society for Precision Engineering, January 1, 1998, pp. 359-362.			
	A478	TANIKAWA et al., "Development of Small-sized 3 DOF Finger Module in Micro Hand for Micro Manipulation.", Proc. of IEEE, March 1, 1999, Int'l. conf. on Intelligent Robots and Systems, pp. 876-881.			
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	A480	Translation of Japanese Patent 02-24848, January 26, 1990.			
	A481	Translation of Japanese Patent 02-92603, April 3, 1990.			
	A482	TRILOGY SYSTEMS, "Linear Motors 310.", www.trilogysystems.com, January 1, 2001.			
	A483	UCHIDA et al., "A Mask-to-Wafer Alignment and Gap Setting Method for X-ray Lithography Using Graftings.", Journal Vacuum Science Technology, November 1, 1991, B 9 (6), pp. 3202-3206.			
	A484	US Application No. 09/698,317, Filed 10-27-2000, CHOI et al., "High Precision Orientation Alignment and Gap Control Stages for Imprint Lithography Processes."			
	A485	US Application No. 10/463,396, Filed 06-17-2003, CHOI et al., "Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold."			
	A486	US Application No. 10/614,716, Filed 07-07-2003, SREENIVASAN et al., "A Conforming Template for Patterning Liquids Disposed on Substrates."			
MJ	A487	US Application No. 10/666,527, Filed 09-18-03, BAILEY et al., "Imprint Lithography Templates having Alignment Marks."			

Examiner Signature	<i>Marc S. Zimmer</i>	Date Considered	<i>6/26/05</i>
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Substitute for form 1449B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/789,319
(use as many sheets as necessary)				Filing Date	02/27/2004
Sheet	24	of	25	First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS						
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.				T ²
<i>M</i>	A488	US Application No. 10/677,639, Filed 10-02-03, MCMACKIN et al., "Single Phase Fluid Imprint Lithography Method."				
	A489	US Application No. 10/687,519, Filed 10-16-2003, TRUSKETT et al., "Low Surface Energy Templates."				
	A490	US Application No. 10/687,562, Filed 10-16-03, CHERALA et al., "Applying Imprinting Material to Substrates Employing Electromagnetic Fields."				
	A491	US Application No. 10/694,284, Filed 10-27-03, XU, "Methods for Fabricating Patterned Features Utilizing Imprint Lithography."				
	A492	US Application No. 10/760,821, Filed 01-20-2004, SREENIVASAN et al., "Method for Concurrently Employing Differing Materials to Form a Substrate."				
	A493	US Application No. 10/784,911, Filed 02-23-04, XU, "Materials for Imprint Lithography."				
	A494	US Application No. 10/785,248, Filed 02-24-2004, CHOI et al., "A Method to Control the Relative Position Between a Body and a Surface."				
	A495	US Application No. 10/788,700, Filed 02-27-2004, SREENIVASAN et al., "Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography."				
	A496	US Application No. 10/864,214, Filed 6-9-04, SREENIVASAN et al., "An Imprint Lithography System to Produce a Light to Impinge upon and Polymerize a Liquid in Superimposition with Template Overlay Marks."				
	A497	US Application No. 10/898,034 Filed 07-23-04, MCMACKIN et al., "A Method of Creating a Turbulent Flow of Fluid between a Mold and a Substrate."				
<i>M</i>	A498	US Application No. 10/898/037, Filed 07-23-04, MCMACKIN et al., "A System of Creating a Turbulent Flow of Fluid between a Mold and a Substrate."				

Examiner Signature	<i>Marc Zimmer</i>	Date Considered	6/21/05
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Application Number	10/789,319				
Filing Date	02/27/2004				
First Named Inventor	Xu et al.				
Group Art Unit	1712				
Examiner Name	Zimmer, Marc S.				
Sheet	25	of	25	Attorney Docket Number	P121-63-03

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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MJ	A499	US Application No. 60/394,458, Filed 07-08-2002, SREENIVASAN et al., "Method and Apparatus for Whole Wafer Planarization using Optical Flats and Light Curable Liquids."	
	A500	US Applications No. 10/616,294, Filed 07-09-2003, CHOI et al., "Systems for Magnification and Distortion Correction for Imprint Lithography Processes."	
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	A502	WANG et al., "Passive Compliance versus Active Compliance in Robot-Based Automated Assembly Systems.", Industrial Robot, January 1, 1998, Vol. 25, No. 1, pp. 48-57.	
	A503	WHITE et al., "Novel Alignment System for Imprint Lithography.", J. Vac. Sci. Technol. B 18(6), November 1, 2000, pp. 3552-3556.	
	A504	WILLIAMS et al., "Six Degree of Freedom Mag-Lev Stage Development.", SPIE, January 1, 1997, Vol. 3051, pp. 856-867.	
	A505	WU, "Large Area High Density Quantized Magnetic Disks Fabricated Using Nanoimprint Lithography.", J. Vac. Sci. Technol., November 1, 1998, B 16(6), pp. 3825-3829.	
	A506	XIA et al., "Soft Lithography.", Angew. Chem. Int. Ed., January 1, 1998, pp. 551-575.	
MJ	A507	XIA et al., "Soft Lithography.", Annu Rev. Mater. Sci., 1998, 28: 153-184.	

Examiner
Signature

Marc Zimmer

Date
Considered

1/6/05

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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

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Title of Invention	COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-CONTAINING MATERIAL							
Application Number :	10/789319							
Confirmation Number:	9202							
First Named Applicant:	Frank Xu							
Attorney Docket Number:	P121-63-03							
Art Unit:	1712							
Examiner:	Marc S. Zimmer							
Search string:			(6468642 or 5542978 or 5837314 or 6565776 or 6503914 or 6649272 or 6204343 or 4614667 or 3810874 or 6737489 or 6721529 or 6664306 or 6790905 or 6544594 or 6774183 or 6830819 or 6802870 or 5389696).pn					
US Patent Documents								
Note: Applicant is not required to submit a paper copy of cited US Patent Documents								
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass	
1	6468642	2002-10-22	Bray et al.	B1				
2	5542978	1996-08-06	Kindt-Larsen et al.					
3	5837314	1998-11-17	Beaton et al.					
4	6565776	2003-05-20	Li et al.	B1				
5	6503914	2003-01-07	Benish et al.	B1				
6	6649272	2003-11-18	Moore et al.	B2				
7	6204343	2001-03-20	Barucha et al.	B1				
8	4614667	1986-09-30	Larson et al.					
9	3810874	1974-05-14	Mitsch et al.					
10	6737489	2004-05-18	Linert et al.	B2				
11	6721529	2004-04-13	Chen et al.	B2				
12	6664306	2003-12-16	Gaddam et al.	B2				
13	6790905	2004-09-14	Fitzgerald et al.	B2				
14	6544594	2003-04-08	Linford et al.	B2				
15	6774183	2004-08-10	Palumbo et al.	B1				
16	6830819	2004-12-14	Kaplan et al.	B2				
17	6802870	2004-10-12	Chang et al.	B2				
18	5389696	1995-02-14	Dempsey et al.					

Signature *Marc Zimmer* *6/13/05*